

IN THE CLAIMS

Please amend the claims as follows:

Claims 1-3 (Canceled).

Claim 4 (Currently Amended): An optical deflection apparatus that changes a reflection direction of an incident light flux, the optical deflection apparatus comprising: The optical deflection apparatus as claimed in claim 1  
a member including a light reflection region; and  
an electret member that contributes at least in part to a generation of an electrostatic attraction force, the electrostatic attraction force subjecting the member including the light reflection region to at least one of a displacement and a deformation,  
wherein the member including the light reflection region has a torsion beam configuration.

Claim 5 (Canceled).

Claim 6 (Currently Amended): An optical deflection apparatus that changes a reflection direction of an incident light flux, the optical deflection apparatus comprising: The optical deflection apparatus as claimed in claim 1  
a member including a light reflection region; and  
an electret member that contributes at least in part to a generation of an electrostatic attraction force, the electrostatic attraction force subjecting the member including the light reflection region to at least one of a displacement and a deformation,  
wherein the member including the light reflection region has a dual side fixed beam configuration.

Claim 7 (Original): An optical deflection apparatus that changes a reflection direction of an incident light flux, the optical deflection apparatus comprising:

- a substrate;
- a plurality of regulating members having stoppers and being implemented at a plurality of edge portions of the substrate;
- a fulcrum member being implemented on the substrate;
- a sheet member including a light reflection region and an electret member, and being movably disposed within a space created by the substrate, the fulcrum member, and the stoppers; and
- a plurality of electrodes being implemented on the substrate and arranged substantially opposite to the sheet member;

wherein the sheet member is subjected to at least one of a displacement and a deformation by an electrostatic force generated with respect to the electret member and the electrodes.

Claim 8 (Original): The optical deflection apparatus as claimed in claim 7, wherein:

- the fulcrum member is arranged to divide the substrate substantially in half;
- the electrodes are arranged such that a first electrode is implemented on one side of the fulcrum member and a second electrode is implemented on the other side of the fulcrum member; and

a one-axis two-dimensional optical deflection is realized by tilting the sheet member around the fulcrum member.

Claim 9 (Original): The optical deflection apparatus as claimed in claim 8, wherein:

a first electric potential that is substantially equivalent to an electric potential of the electret member is applied to one of the first and second electrodes;

a second electric potential is applied to the other one of the first and second electrodes; and

the sheet member is tilted by switching between applying the first electric potential and the second electric potential to the first electrode and the second electrode.

**Claim 10 (Original):** The optical deflection apparatus as claimed in claim 9, wherein the second electric potential corresponds to a ground potential.

**Claim 11 (Original):** The optical deflection apparatus as claimed in claim 7, wherein an inorganic material is used for the electret member.

**Claim 12 (Original):** The optical deflection apparatus as claimed in claim 11, wherein at least one of a metal oxide film, a metal oxinitride film, and a metal nitride film is used as the inorganic material.

**Claim 13 (Original):** The optical deflection apparatus as claimed in claim 11, wherein a silicon oxide film is used as the inorganic material.

**Claim 14 (Original):** The optical deflection apparatus as claimed in claim 11, wherein a silicon nitride film is used as the inorganic material.

**Claim 15 (Original):** The optical deflection apparatus as claimed in claim 11, wherein an aluminum nitride film is used as the inorganic material.

Claim 16 (Original): An optical deflection apparatus manufacturing method, comprising the steps of:

forming a fulcrum member on a substrate;  
forming a plurality of electrodes on the substrate;  
depositing and planarizing a first sacrificial layer over the electrodes;  
depositing an electret member on the first sacrificial layer;  
charging the electret member to a predetermined electric potential;  
depositing a member including a light reflection region on the electret member;  
patterning the electret member and the member including the light reflection region to form a sheet member;  
depositing a second sacrificial layer on the sheet member;  
patterning the first sacrificial layer and the second sacrificial layer;  
patterning a plurality of regulating members having stoppers to a position where the first and second sacrificial layers are patterned; and  
removing the patterned first and second sacrificial layers through etching.

Claim 17 (Original): The optical deflection apparatus manufacturing method as claimed in claim 16, wherein an inorganic material is used for the electret member.

Claim 18 (Original): The optical deflection apparatus manufacturing method as claimed in claim 17, wherein at least one of a metal oxide film, a metal oxinitride film, and a metal nitride film is used as the inorganic material.

Claim 19 (Original): The optical deflection apparatus manufacturing method as claimed in claim 17, wherein a silicon oxide film is used as the inorganic material.

Claim 20 (Original): The optical deflection apparatus manufacturing method as claimed in claim 17, wherein a silicon nitride film is used as the inorganic material.

Claim 21 (Original): The optical deflection apparatus manufacturing method as claimed in claim 17, wherein an aluminum nitride film is used as the inorganic material.

Claim 22 (Currently Amended): An optical deflection array that is adapted to change a reflection direction of an incident light flux, the optical deflection array comprising:

an optical deflection apparatus including a member having a light reflection region, and an electret member that contributes to a generation of an electrostatic attraction force, the electrostatic attraction force subjecting the member having the light reflection region to at least one of a displacement and a deformation;

wherein a plurality of the optical deflection apparatuses are laid out in at least one of a one-dimensional arrangement and a two-dimensional arrangement, and

the member including the light reflection region has a torsion beam configuration.

Claim 23 (Original): An optical deflection array that is adapted to change a reflection direction of an incident light flux, the optical deflection array comprising: an optical deflection apparatus including a substrate, a plurality of regulating members having stoppers and being implemented at a plurality of edge portions of the substrate, a fulcrum member being implemented on the substrate, a sheet member including an electret member and a light reflection region, and being movably disposed within a space created by the substrate, the fulcrum member, and the stoppers, and a plurality of electrodes being implemented on the substrate and arranged substantially opposite to the electret member, the sheet member being

subjected to at least one of a displacement and a deformation by an electrostatic attraction force generated with respect to the electret member and the electrodes; wherein a plurality of the optical deflection apparatuses are laid out in at least one of a one-dimensional arrangement and a two-dimensional arrangement.

Claim 24 (Original): An imaging apparatus that is adapted to form a latent image by conducting optical writing on a photoconductor, the imaging apparatus comprising:

an optical write unit including an optical deflection array that is adapted to change a reflection direction of an incident light flux, the optical deflection array implementing an optical deflection apparatus including a member having a light reflection region, and an electret member that contributes to a generation of an electrostatic attraction force, the electrostatic attraction force subjecting the member having the light reflection region to at least one of a displacement and a deformation, wherein a plurality of the optical deflection apparatuses are laid out in at least one of a one-dimensional arrangement and a two-dimensional arrangement.

Claim 25 (Original): An imaging apparatus that is adapted to form a latent image by conducting optical writing on a photoconductor, the imaging apparatus comprising:

an optical write unit including an optical deflection array that is adapted to change a reflection direction of an incident light flux, the optical deflection array implementing an optical deflection apparatus including a substrate, a plurality of regulating members having stoppers and being implemented at a plurality of edge portions of the substrate, a fulcrum member being implemented on the substrate, a sheet member including an electret member and a light reflection region, and being movably accommodated within a space created by the substrate, the fulcrum member, and the stoppers, and a plurality of electrodes being

implemented on the substrate, and arranged substantially opposite to the electret member, the sheet member being subjected to at least one of a displacement and a deformation by an electrostatic force that is generated with respect to the electret member and the electrodes, wherein a plurality of the optical deflection apparatuses are laid out in at least one of a one-dimensional arrangement and a two-dimensional arrangement.

Claim 26 (Original): An image projection display apparatus that is adapted to display a projection image based on image information, the image projection apparatus comprising:

a display unit that reflects an optical signal from a light source in a desired direction according to the image information, the display unit including an optical deflection array that implements an optical deflection apparatus including a member having a light reflection region, and an electret member that contributes to a generation of an electrostatic attraction force, the electrostatic attraction force subjecting the member having the light reflection region to at least one of a displacement and a deformation, wherein a plurality of the optical deflection apparatuses are laid out in at least one of a one-dimensional arrangement and a two-dimensional arrangement.

Claim 27 (Original): An image projection display apparatus that is adapted to display a projection image based on image information, the image projection apparatus comprising:

a display unit that reflects an optical signal from a light source in a desired direction according to the image information, the display unit including an optical deflection array that implements an optical deflection apparatus including a substrate, a plurality of regulating members having stoppers and being implemented at a plurality of edge portions of the substrate, a fulcrum member being implemented on the substrate, a sheet member including an electret member and a light reflection region, and being movably accommodated within a

space created by the substrate, the fulcrum member, and the stoppers, and a plurality of electrodes being implemented on the substrate, and arranged substantially opposite to the electret member, the sheet member being subjected to at least one of a displacement and a deformation by an electrostatic force that is generated with respect to the electret member and the electrodes, wherein a plurality of the optical deflection apparatuses are laid out in at least one of a one-dimensional arrangement and a two-dimensional arrangement.

Claim 28 (New): An optical deflection array that is adapted to change a reflection direction of an incident light flux, the optical deflection array comprising:

an optical deflection apparatus including a member having a light reflection region, and an electret member that contributes to a generation of an electrostatic attraction force, the electrostatic attraction force subjecting the member having the light reflection region to at least one of a displacement and a deformation;

wherein a plurality of the optical deflection apparatuses are laid out in at least one of a one-dimensional arrangement and a two-dimensional arrangement, and

the member including the light reflection region has a dual side fixed beam configuration.